

# PATENT ABSTRACTS OF JAPAN

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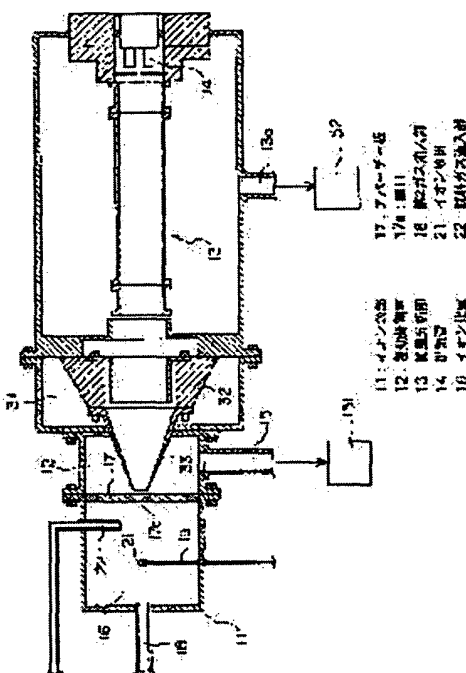
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## (54) IONIZING METHOD FOR MASS SPECTROMETRY AND MASS SPECTROMETER

(57)Abstract:

**PROBLEM TO BE SOLVED:** To provide an ionizing method for mass spectrometry and a mass spectrometer, suppressing the contact of a sample gas with a metal ion emitter, preventing the contamination of the metal ion emitter, and stably conducting the mass spectrometry for a long time.

**SOLUTION:** Metal ions are attached to the sample gas in an ionizing chamber 16 to produce sample gas ions, the sample gas ions are passed through a mass spectrometry part 13 formed with an electromagnetic field and mass-segregated, and the mass-segregated sample gas ions are detected and measured as ion current with a detecting part 14. The metal ion emitter 21 emitting metal ions is arranged in the upstream position of a region controlled in the pressure reducing atmosphere where gas flow becomes viscous flow, a sample gas inflow part 2 introducing the sample gas is arranged in the downstream position where the metal ions are carried, and the ionized sample gas attached with the metal ions is carried to the mass spectrometry part through an opening 17a of an aperture plate 17.



## LEGAL STATUS

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